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Sheet 1 of 1

Substitute Form PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-132001	Application No. 10/053,106
Information Disclosure Statement by Applicant <small>(Use several sheets if necessary)</small> <small>(37 CFR §1.98(b))</small>		Applicant Peter de Groot et al.		
		Filing Date November 2, 2001	Group Art Unit	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
all	AA	5,438,413	08/1995	Mazor et al.			
	AB						
	AC						
	AD						
	AE						
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	AH						
	AI						
	AJ						
	AK						

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Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation
							Yes
	AL						
	AM						
	AN						
	AO						
	AP						

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
	
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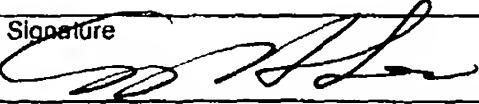
Substitute Disclosure Form (PTO-1449)

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Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>all</i>	AA	6,195,168 B1	02/2001	De Lega et. al.	356	497	
	AB	5,398,113	03/1995	De Groot	356	360	
	AC	5,784,164	07/1998	Deck et. al.	356	511	
<i>c</i>	AD	5,402,234	03/1995	Deck	356	497	
<i>✓</i>	AE	5,471,303	11/1995	Ai et. al.	356	497	

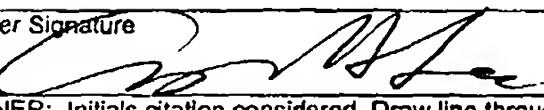
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	AF						
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Other Documents (include Author, Title, Date, and Place of Publication)		
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<i>all</i>	AK	P. de Groot and Leslie Deck, "Surface profiling by analysis of white-light interferograms in the spatial frequency domain," <i>J. Mod. Opt.</i> 42(2), 389-401 (1995).
	AL	T. Dresel, G. Haesler and H. Venzke, "Three-dimensional sensing of rough surfaces by coherence radar," <i>Appl. Opt.</i> 31(7), 919-925 (1992).
	AM	Gordon S. Kino and Stanley S. C. Chim, "Mirau correlation microscope," <i>Appl. Opt.</i> 29(26), 3775-3783 (1990).
	AN	Kieran G. Larkin, "Efficient nonlinear algorithm for envelope detection in white light interferometry," <i>J. Opt. Soc. Am. A</i> 4, 832- 843 (1996)
	AO	M.-C. Park and S.-W. Kim, "Direct quadratic polynomial fitting for fringe peak detection of white light scanning interferograms", <i>Opt. Eng.</i> 39(4) 952-959 (2000)
	AP	A. Harasaki, J. Schmit and J. C. Wyant, "Improved vertical-scanning interferometry", <i>Appl. Opt.</i> 13(39), 2107-2115 (2000)
<i>✓</i>	AQ	B.L. Danielson and C.Y. Boisrobert, "Absolute optical ranging using low coherence interferometry," <i>Appl. Opt.</i> 30(21), 2975-2979 (1991)
	AR	A. Harasaki and J. C. Wyant, "Fringe modulation skewing effect in white-light vertical scanning interferometry," <i>Appl. Opt.</i> 39(13), 2101-2106 (2000).

Examiner Signature 	Date Considered <i>8/26/02</i>
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JUN 03 2002 U.S. PATENT AND TRADEMARK OFFICE O P E JC26 E			
(37 CFR §1.98(b))		Attorney's Docket No. 09712-132001	Application No. 10/053,106
Applicant Peter de Groot et al.			
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<i>all</i>	AS	D. C. Ghiglia and W. E. Pritt, "Two-dimensional phase unwrapping: Theory, algorithms and software" (John Wiley & Sons, Inc., New York, 1998), p. 93.
	AT	J. Schwider and L. Zhou, "Dispersive interferometric profilometer," Opt. Lett. 19(13), 995-997 (1994).
	AU	S.W. Kim and G.H. Kim, "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry." Appl. Opt. 38(28) (1999).
	AV	M. Davidson, K. Kaufman, and I. Mazor, "The coherence probe microscope," Solid State Technology, 30(9) 57-59 (1987).
	AW	J.C. Wyant, "How to extend interferometry for rough-surface tests," Laser Focus World, 131-135 (September 1993).
	AX	P. de Groot and L. Deck, "Three-dimensional imaging by sub-Nyquist sampling of white-light interferograms," Opt. Lett. 18(17), 1462-1464 (1993).
	AY	P. Sandoz, R. Devillers, and A. Plata, "Unambiguous profilometry by fringe-order identification in white-light phase shifting interferometry," J. Mod. Opt. 44, 519-534 (1997).
	AZ	P.J. Caber, S.J. Martinek, and R.J. Niemann, "A new interferometric profiler for smooth and rough surfaces," SPIE 2088, 195-203 (1993).
	AAA	A. Pfortner and J. Schwider, "Dispersion error in white-light Linnik interferometers and its implications for evaluation procedures," Appl. Opt. 40(34) 6223-6228 (2001).
	ABB	P. de Groot, X. Colonna de Lega, J. Kramer, and M. Turzhitsky, "High precision surface inspection on the microscale by broadband interferometry", Proc. Fringe 2001, The 4 th International Workshop on Automatic Processing of Fringe Patterns, Wolfgang Osten and Werner Juptner Eds., Elsevier, pp. 333-340 (2001).
	ACC	L. Deck and P. de Groot, "High-speed non-contact profiler based on scanning white light interferometry," Appl. Opt. 33(31), 7334-7338 (November 1, 1994).

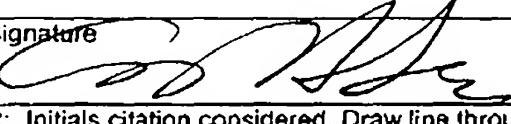
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	AJ	T. Dresel, G. Hausler and H. Venzke, "Three-dimensional sensing of rough surfaces by coherence radar," Appl. Opt. 31(7), 919-925 (1992).
	AK	Gordon S. Kino and Stanley S. C. Chim, "Mirau correlation microscope," Appl. Opt. 29(26), 3775-3783 (1990).
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